



U.S. UTILITY Patent Application

PATENT DATE

SCANNED 70(1) Q.A. Am

ANTS Mohammad Shabani
Shigeru Okuuchi

APPLICANTS

TITLE

Method for analyzing impurities in a silicon substrate and apparatus for decomposing a silicon substrate through vapor-phase reaction

PTO-2040
12/89

ISSUING CLASSIFICATION												
ORIGINAL				CROSS REFERENCE(S)								
CLASS		SUBCLASS		CLASS	SUBCLASS (ONE SUBCLASS PER BLOCK)							
INTERNATIONAL CLASSIFICATION												

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	Sheets Drwg.	Figs. Drwg.	Print Fig.	Total Claims
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